

UNIVERSITY  
OF ŽILINA



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# *Laser interference lithography – principle, automated setup and gratings*

PRESENTED BY DUŠAN PUDIŠ, UNIVERSITY OF ŽILINA



Peter Sagan

KIA motors

**UNIZA - 7 faculties**

124 Study programs (43 Bc / 51 MSc / 30 PhD)  
Students (6835 int / 550 ext)

**Faculty of Electrical Engineering and Information Technology**

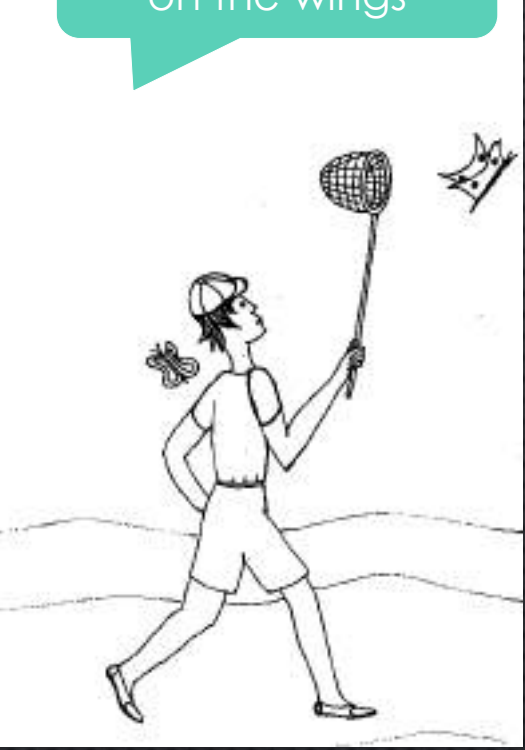
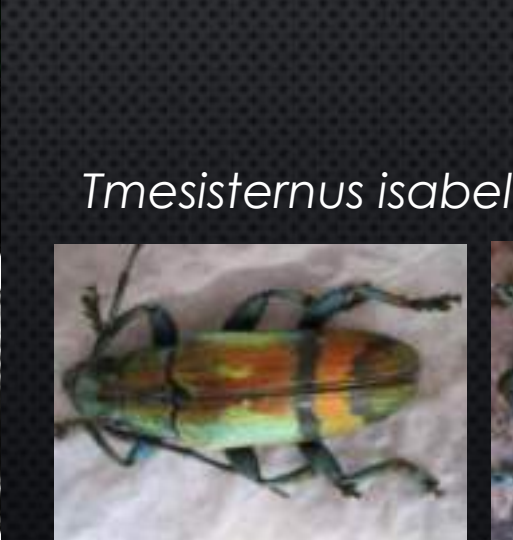
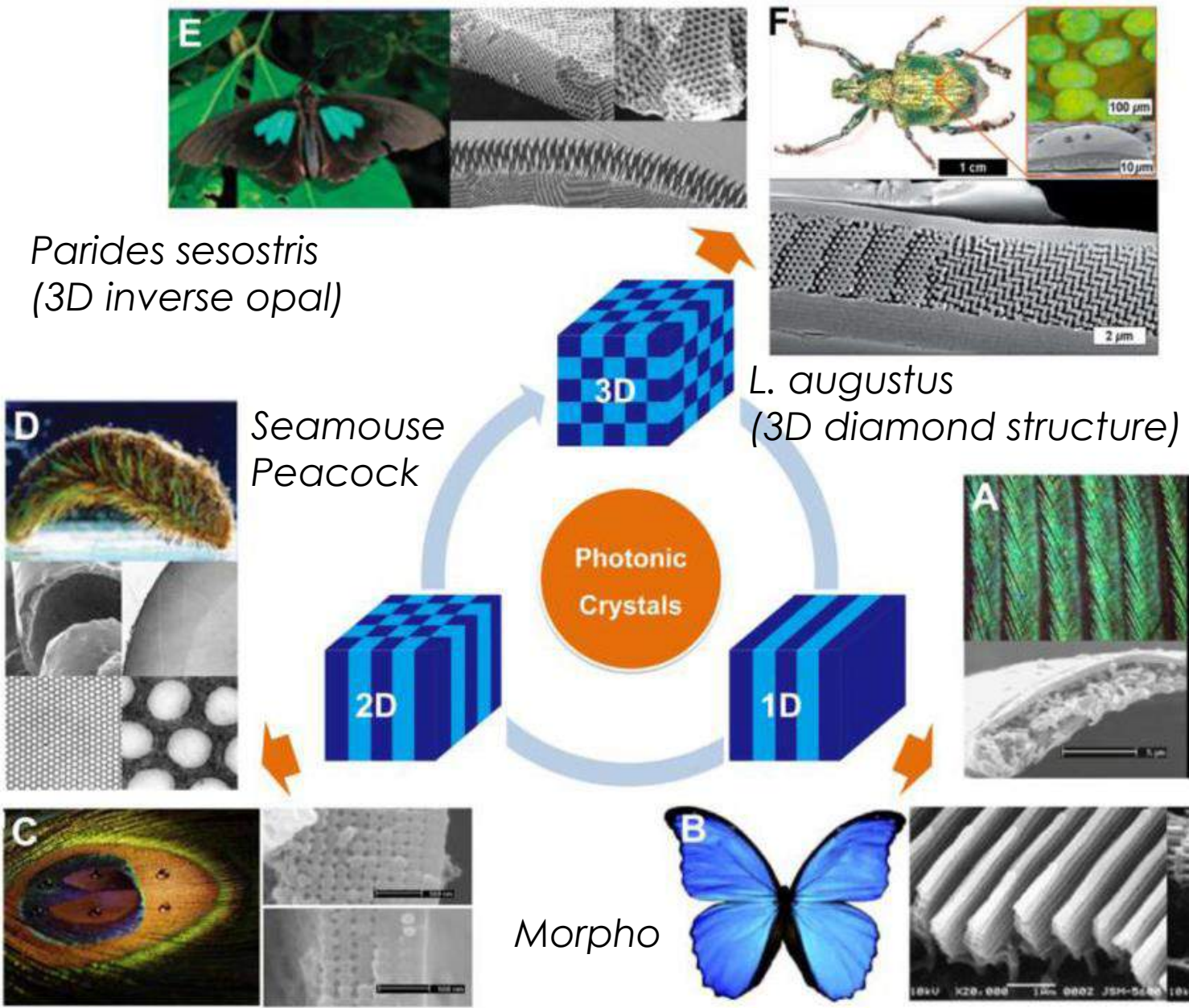
22 Study programs  
Students (1028 int / 29 ext)

University of Žilina (UNIZA)

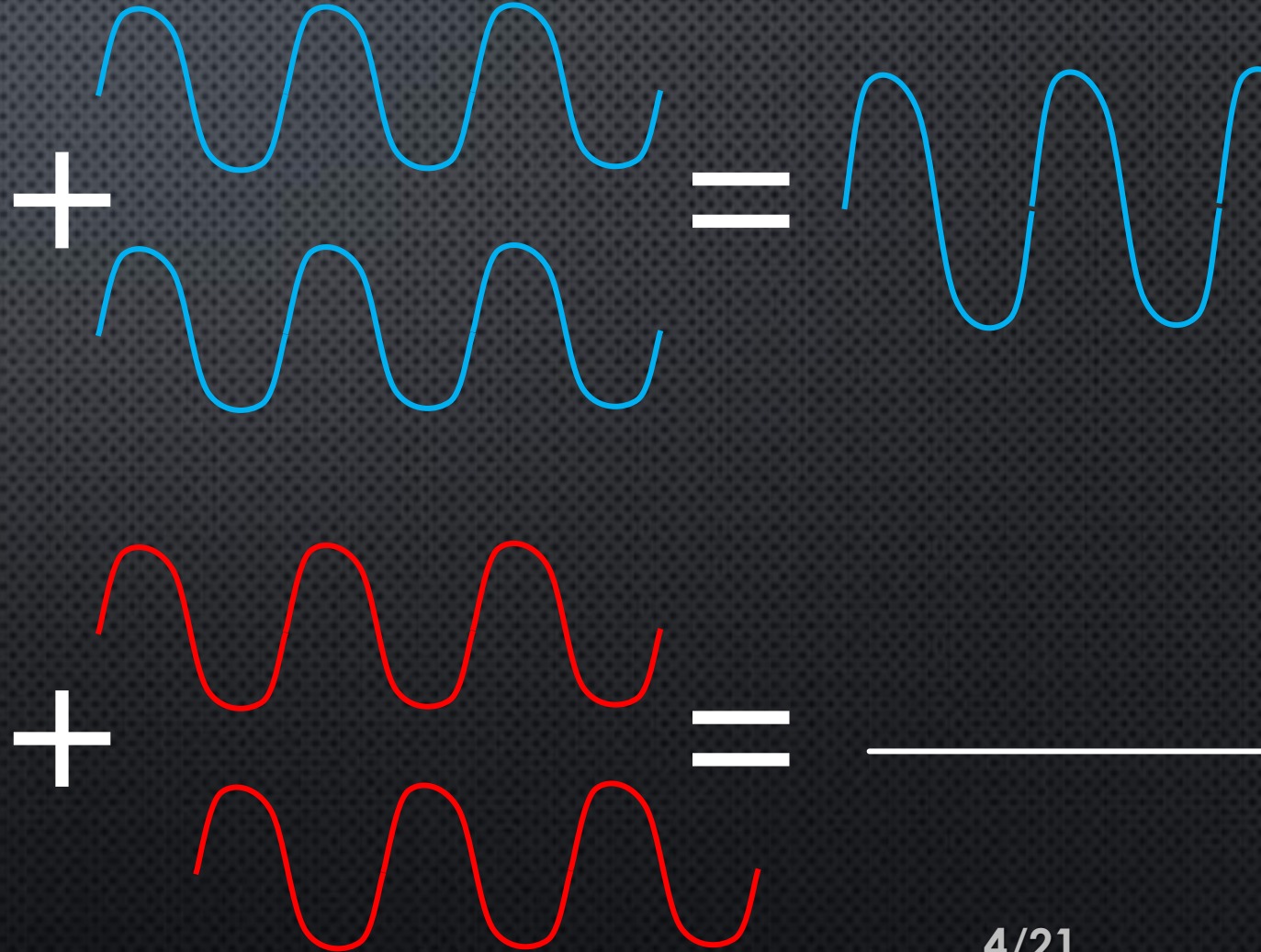
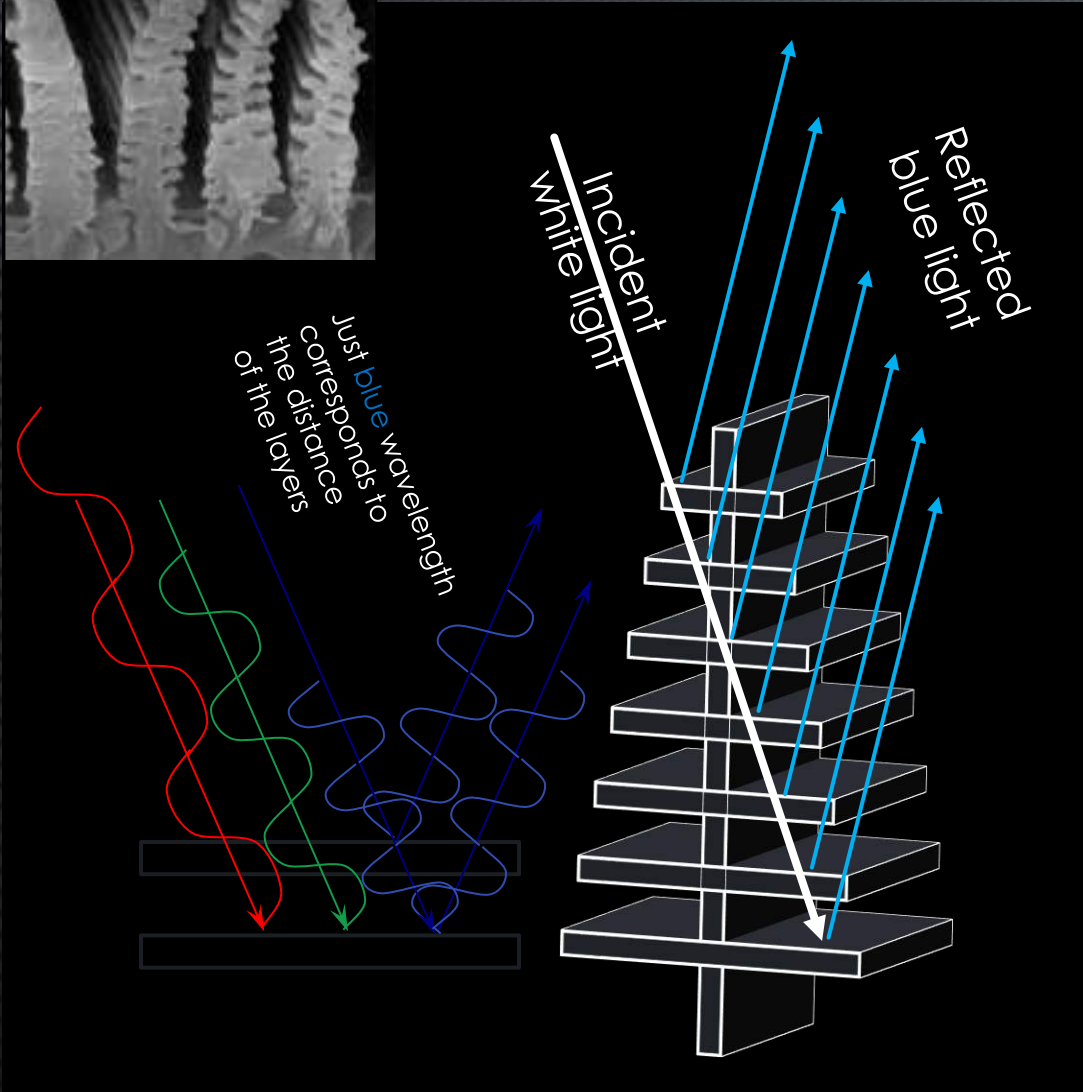
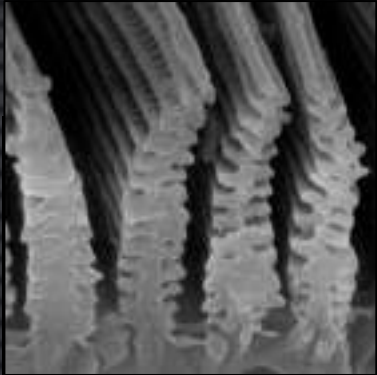


# Gratings inspired by nature

...waa, photonics on the wings



# How it works?



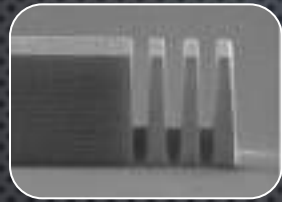
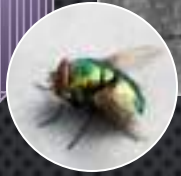
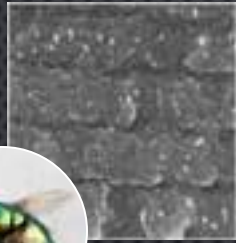
# From nature to technology

Nature

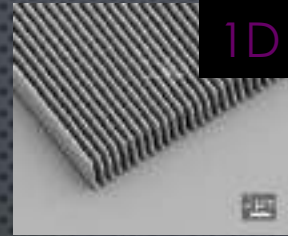
Technology



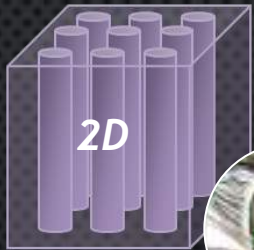
1D



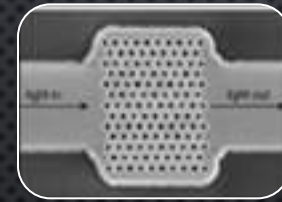
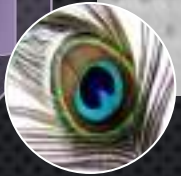
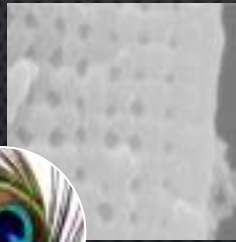
Bragg reflector



1D



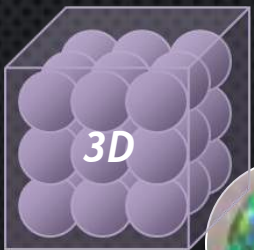
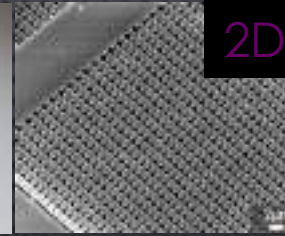
2D



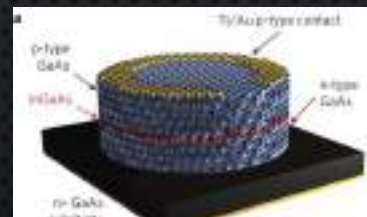
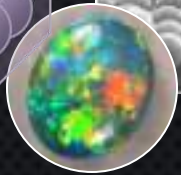
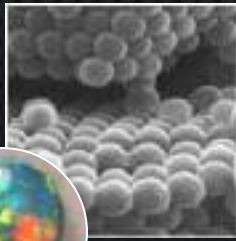
PhC slabs



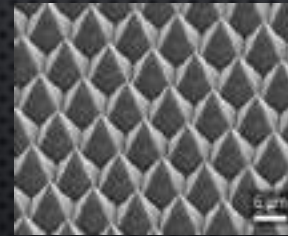
2D



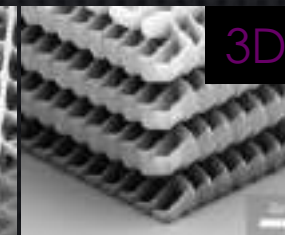
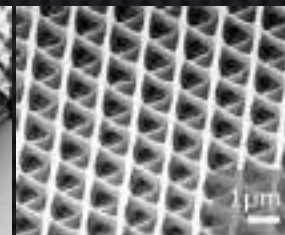
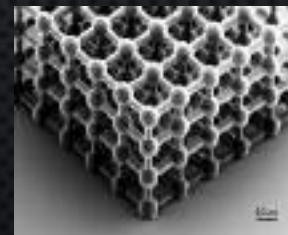
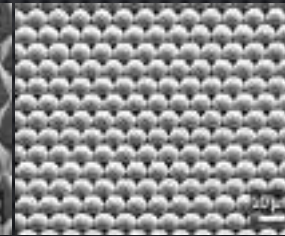
3D



3D PhC laser



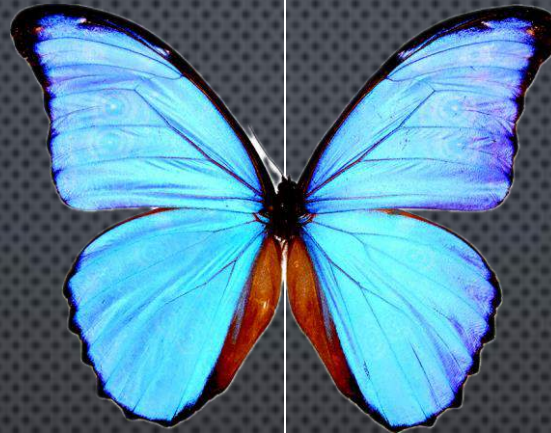
2.5D



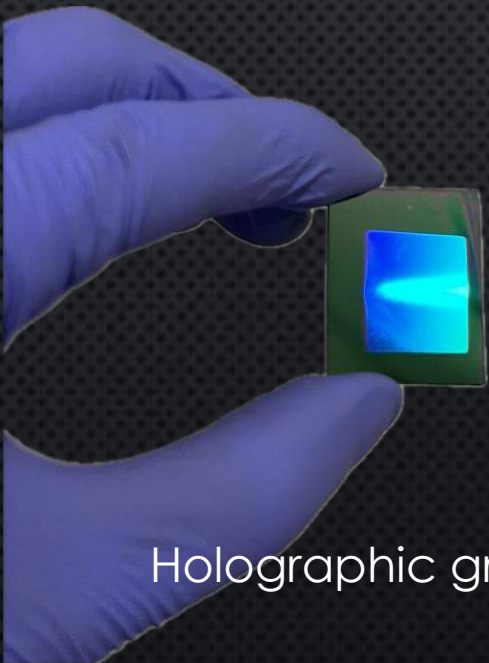
3D

# Interference Lithography | Holographic gratings

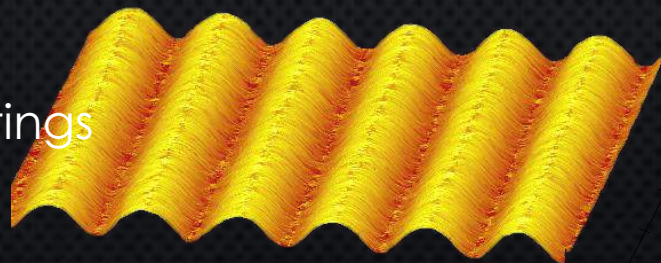
- Large area patterning
- Customizability
- Rapid prototyping
- Sub-micron resolution
- Non-contact fabrication



- Laser systems
- Sensing
- Filters
- Optical communications



Holographic gratings



Grooved gratings



# Laser interference lithography - single exposure

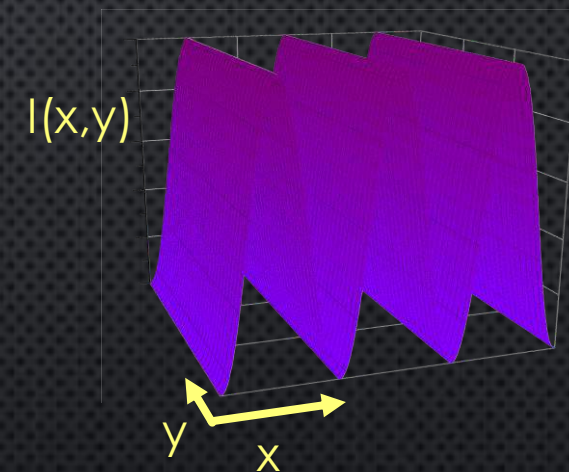
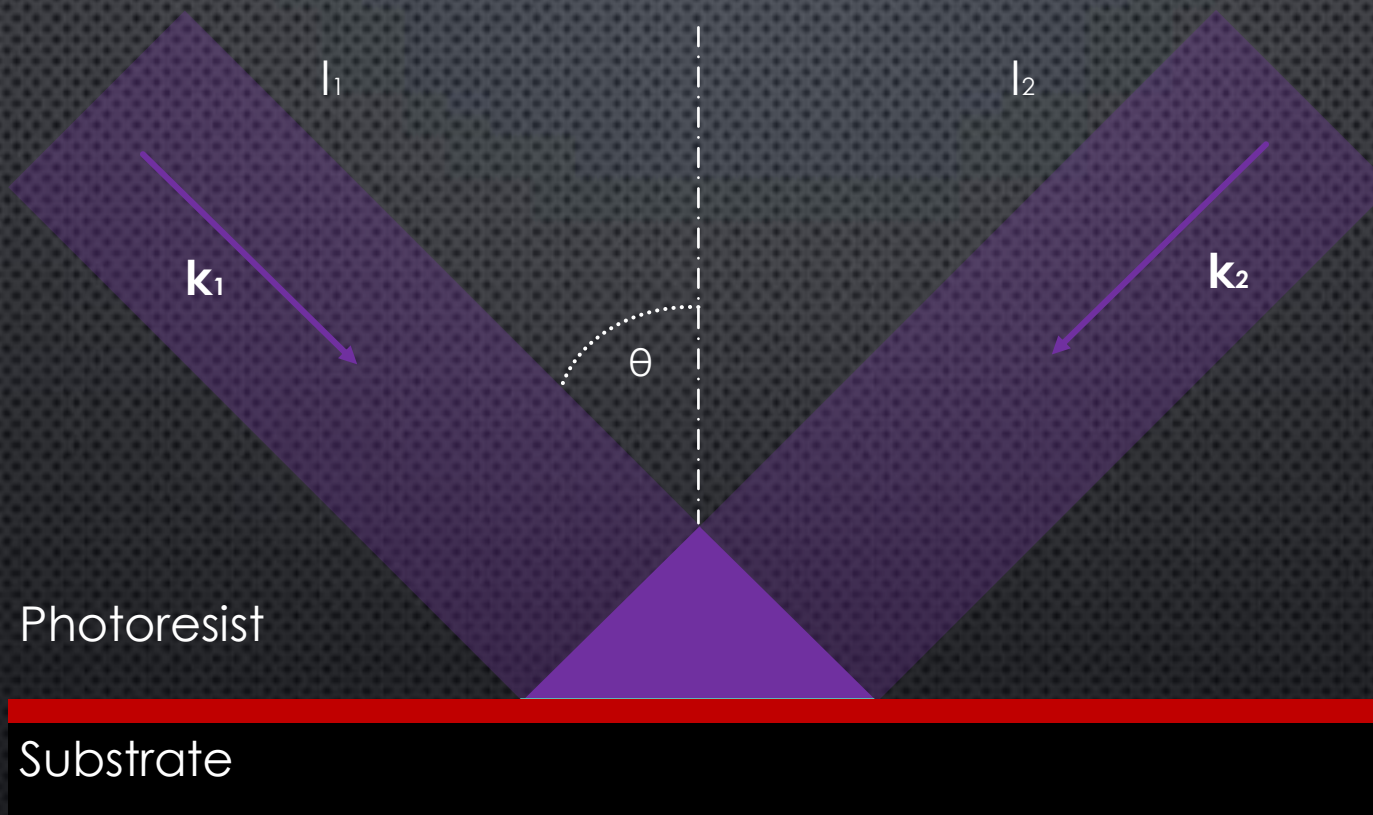
$$E_1 = E_{10}e^{i(\omega t + k_1 \cdot r)} = E_{10}e^{i\phi_1}$$

$$E_2 = E_{20}e^{i(\omega t + k_2 \cdot r)} = E_{20}e^{i\phi_2}$$

$$\Lambda = \frac{\lambda}{2 \sin \theta}$$

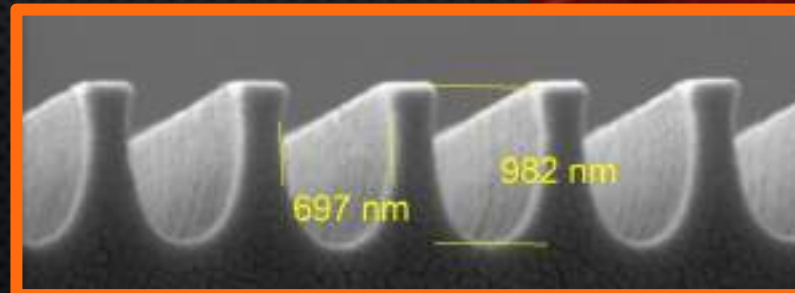
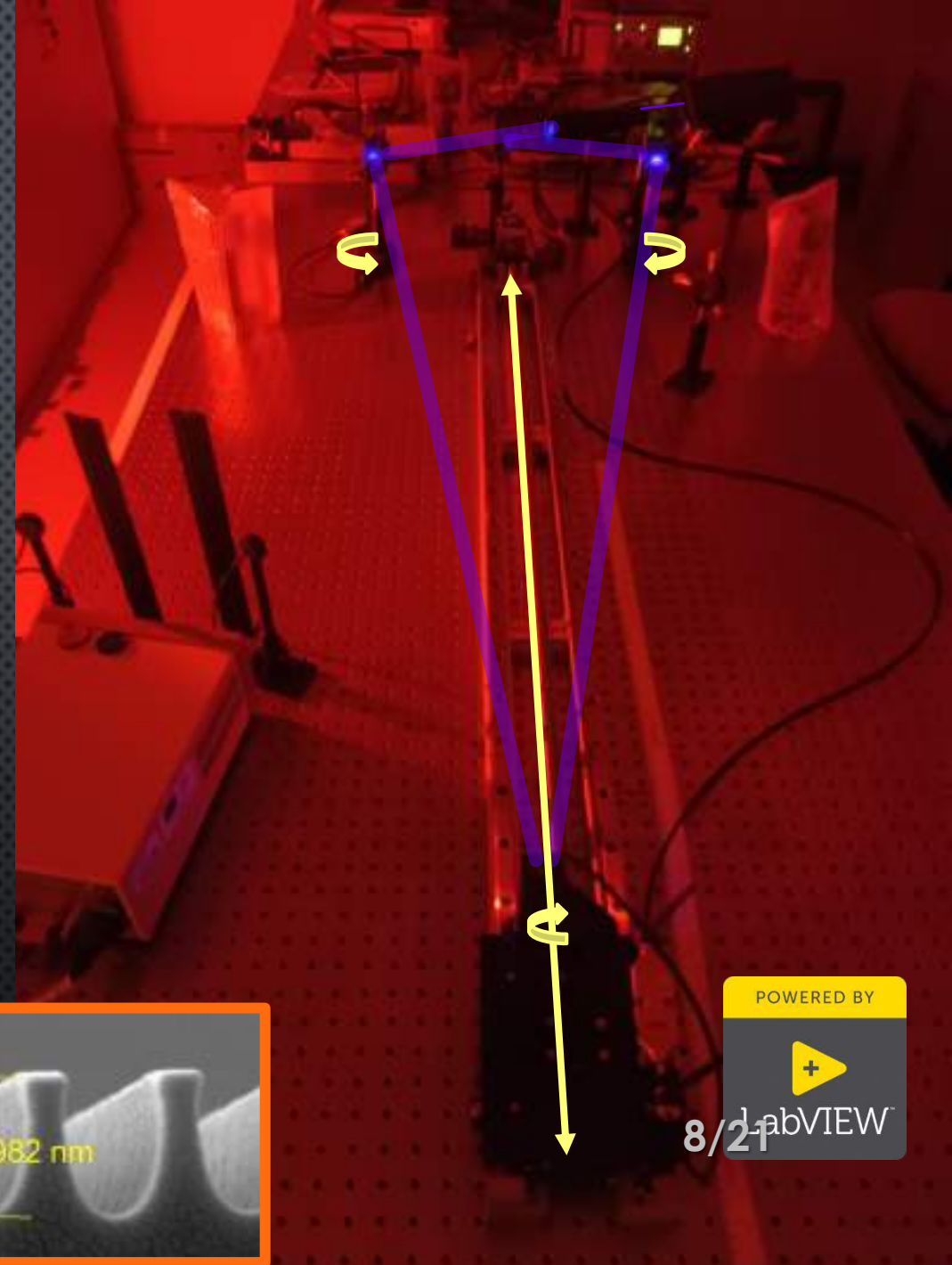
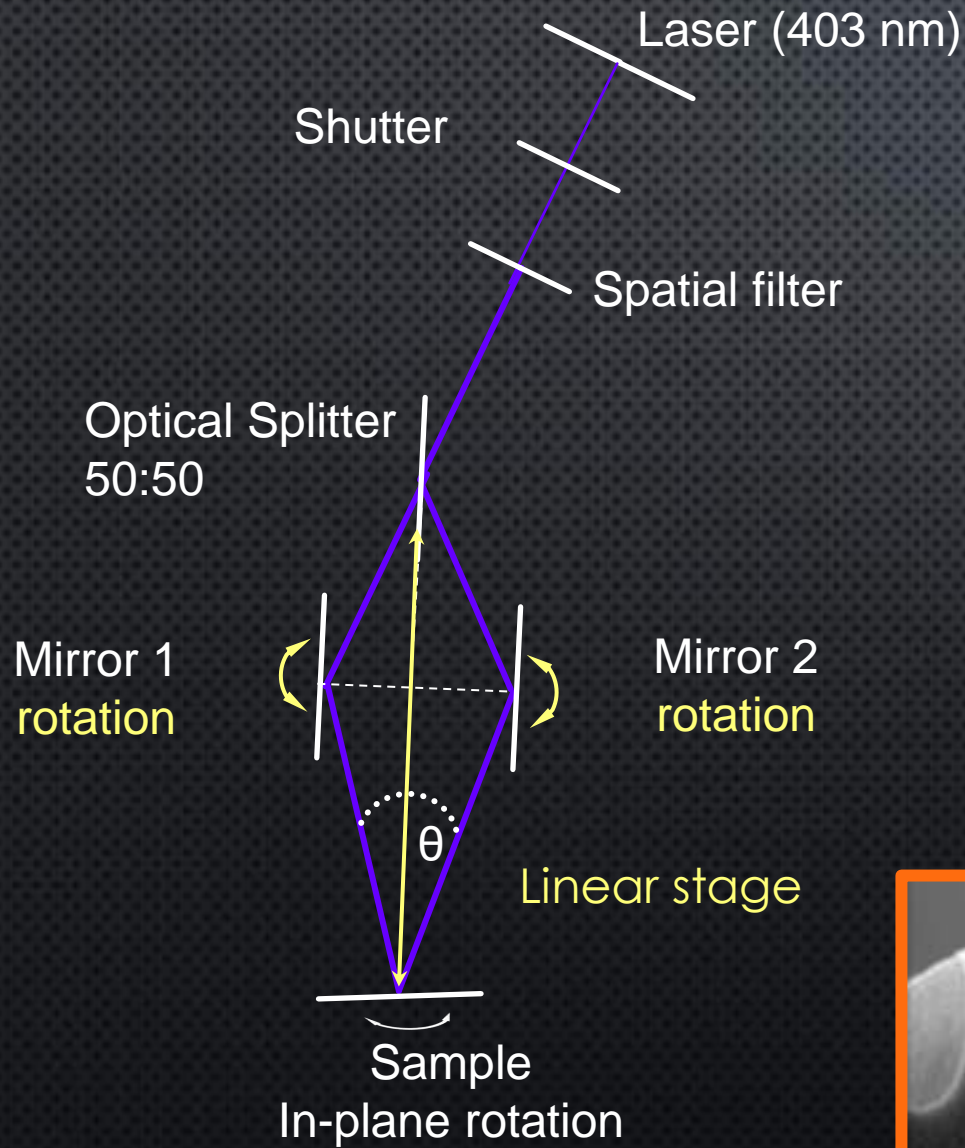
8°	⇔	1500 nm
12°	⇔	1000 nm
24°	⇔	500 nm
54°	⇔	250 nm

405 nm  
Laser



$$I = \sum_{i=1}^n I_i = 4 \sum_{i=1}^n E_{0i}^2 [\cos(kx \sin \theta)(x \sin \alpha_i + y \cos \alpha_i)]^2$$

# Experimental setup of interference lithography



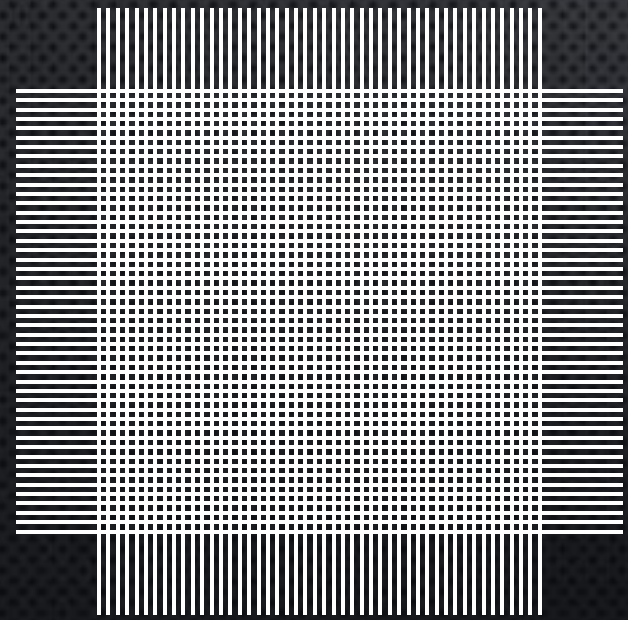


# Laser interference lithography – multiple exposure

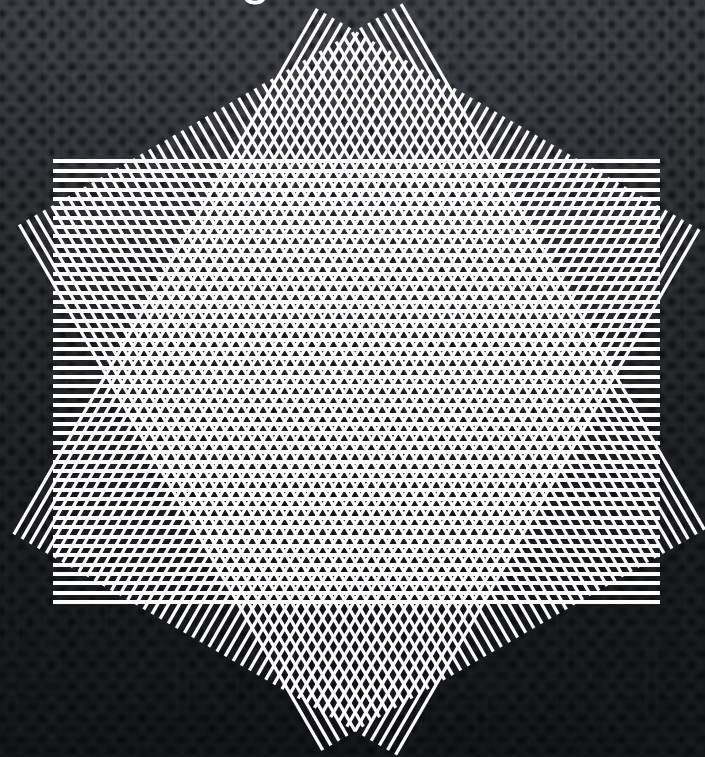
ROTATION AND CUMULATION OF EXPOSURE  
DOSES

- 2D STRUCTURES
- MOIRÉ EFFECT

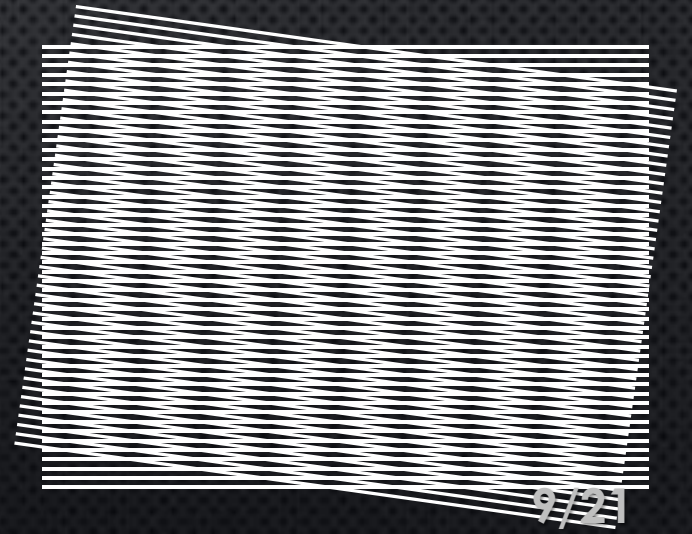
2D square lattice



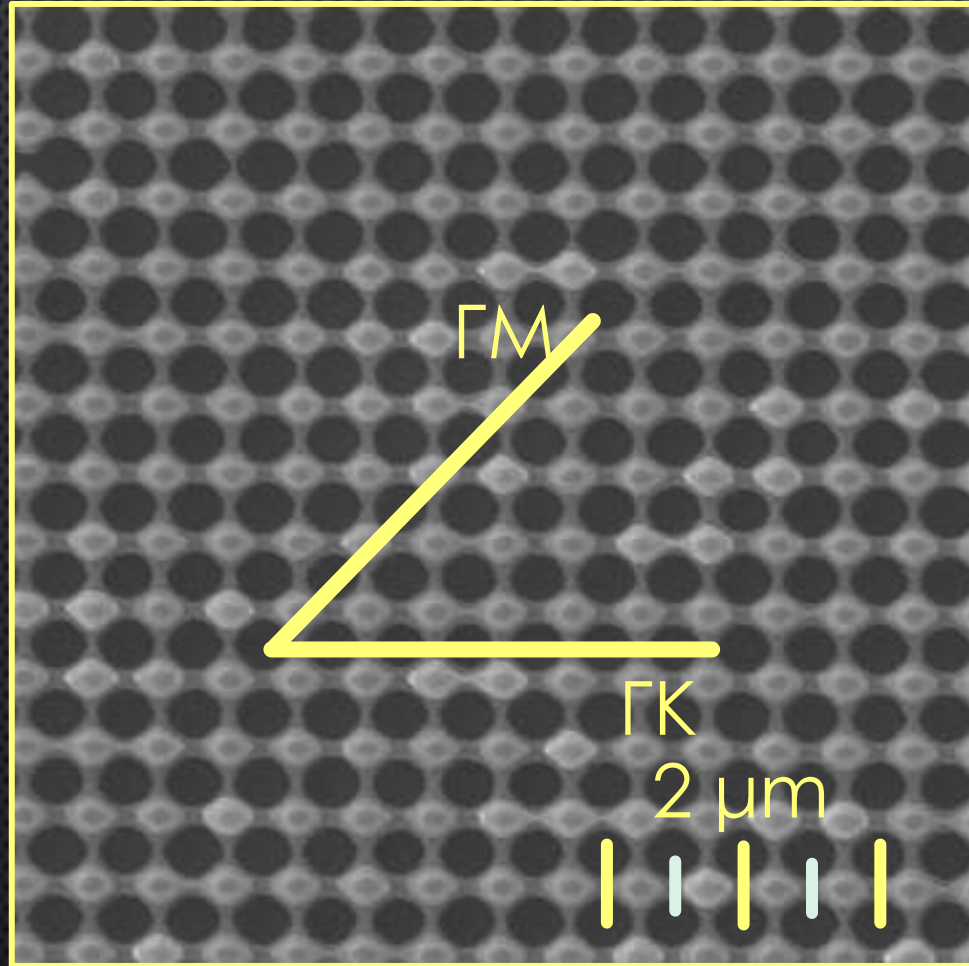
2D triangular lattice



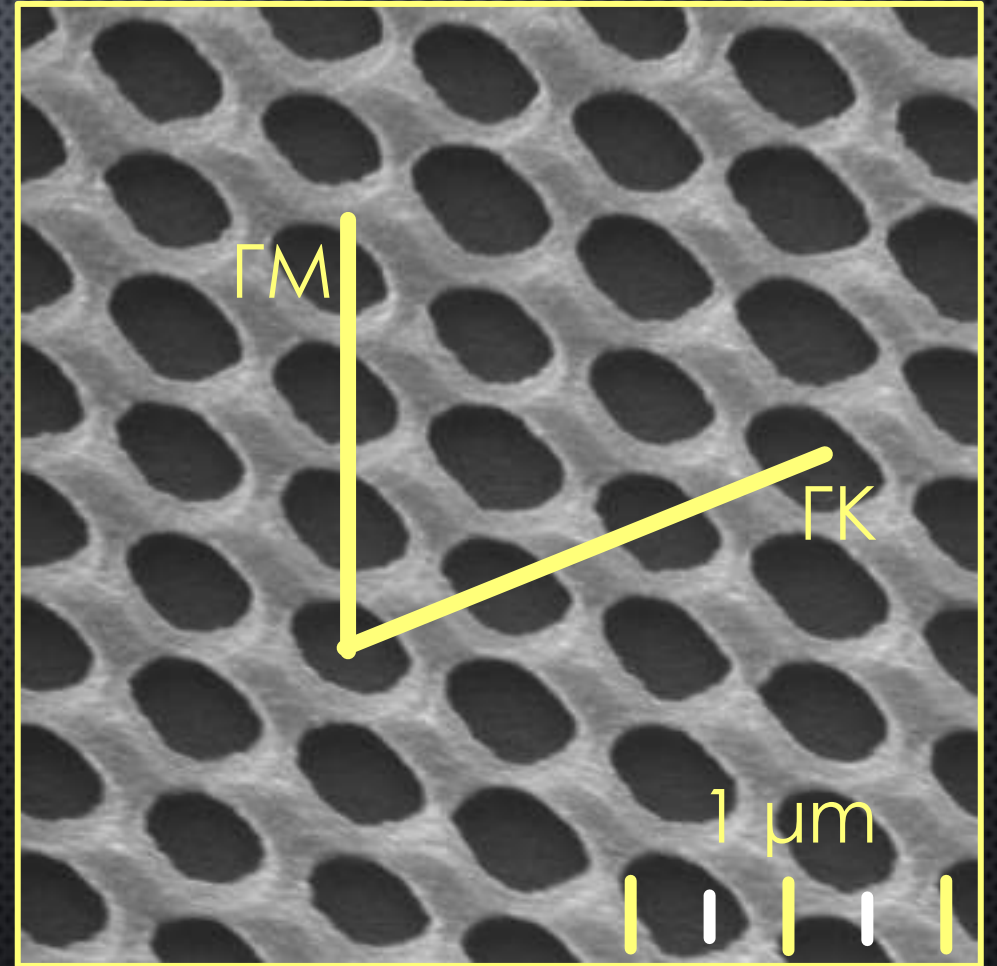
Moiré effect



# Laser interference lithography – multiple exposure



$\Lambda = 500 \text{ nm}$



$\Lambda = 600 \text{ nm}$



**Ultra wide** range of periods

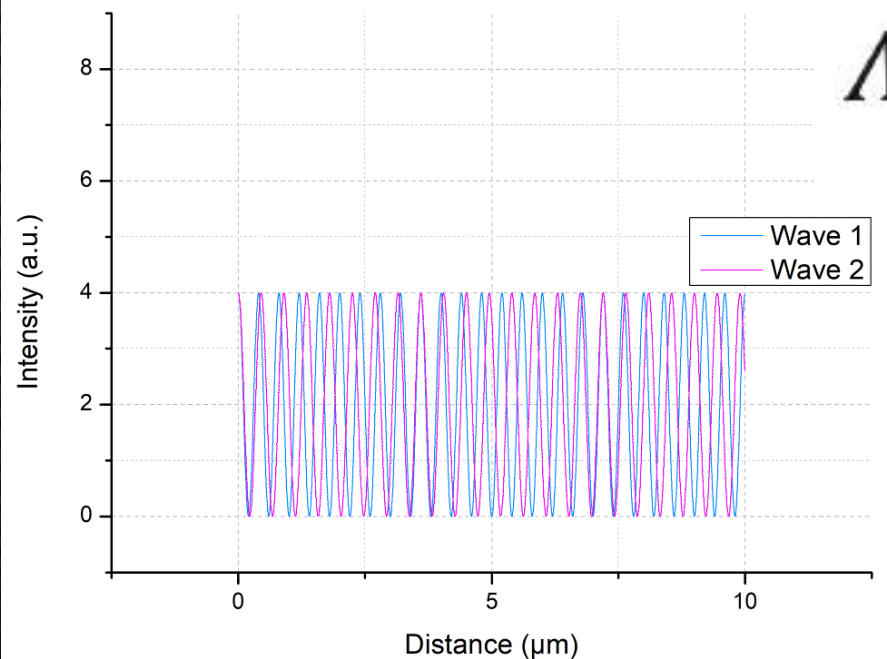
**250 nm**  $\leftrightarrow$  **250 000 nm**  
**( $\lambda/2$ )** **(infinity)**

# Period mixing principle – multiple exposures

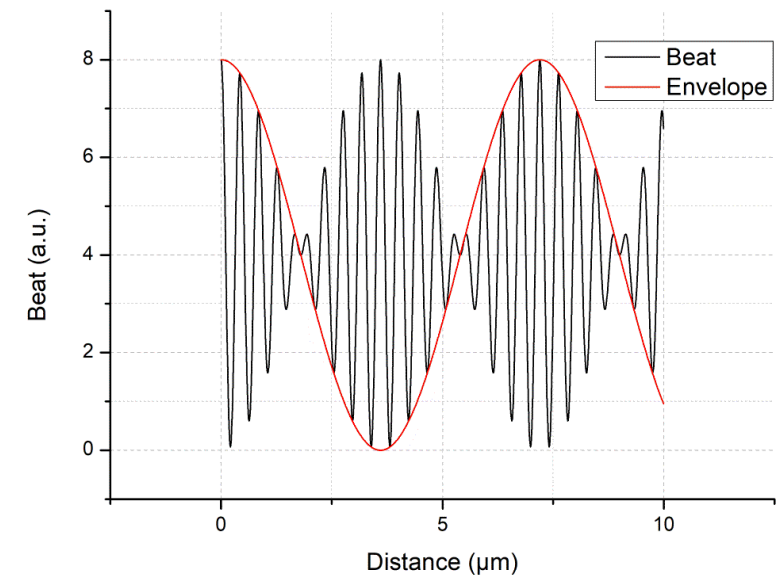
$$I = I_1 + I_2$$

$$I = 4E_0^2 \left[ \cos^2 \left( \frac{\pi}{\Lambda_1} x \right) + \cos^2 \left( \frac{\pi}{\Lambda_2} x \right) \right]$$

$$I = 4E_0^2 + 4E_0^2 \cos \left( \pi \frac{\Lambda_1 + \Lambda_2}{\Lambda_1 \Lambda_2} x \right) \cos \left( \pi \frac{\Lambda_2 - \Lambda_1}{\Lambda_1 \Lambda_2} x \right)$$



$$\Lambda_{env} = \frac{\Lambda_1 \Lambda_2}{\Lambda_2 - \Lambda_1}$$



Wave 1 & Wave 2

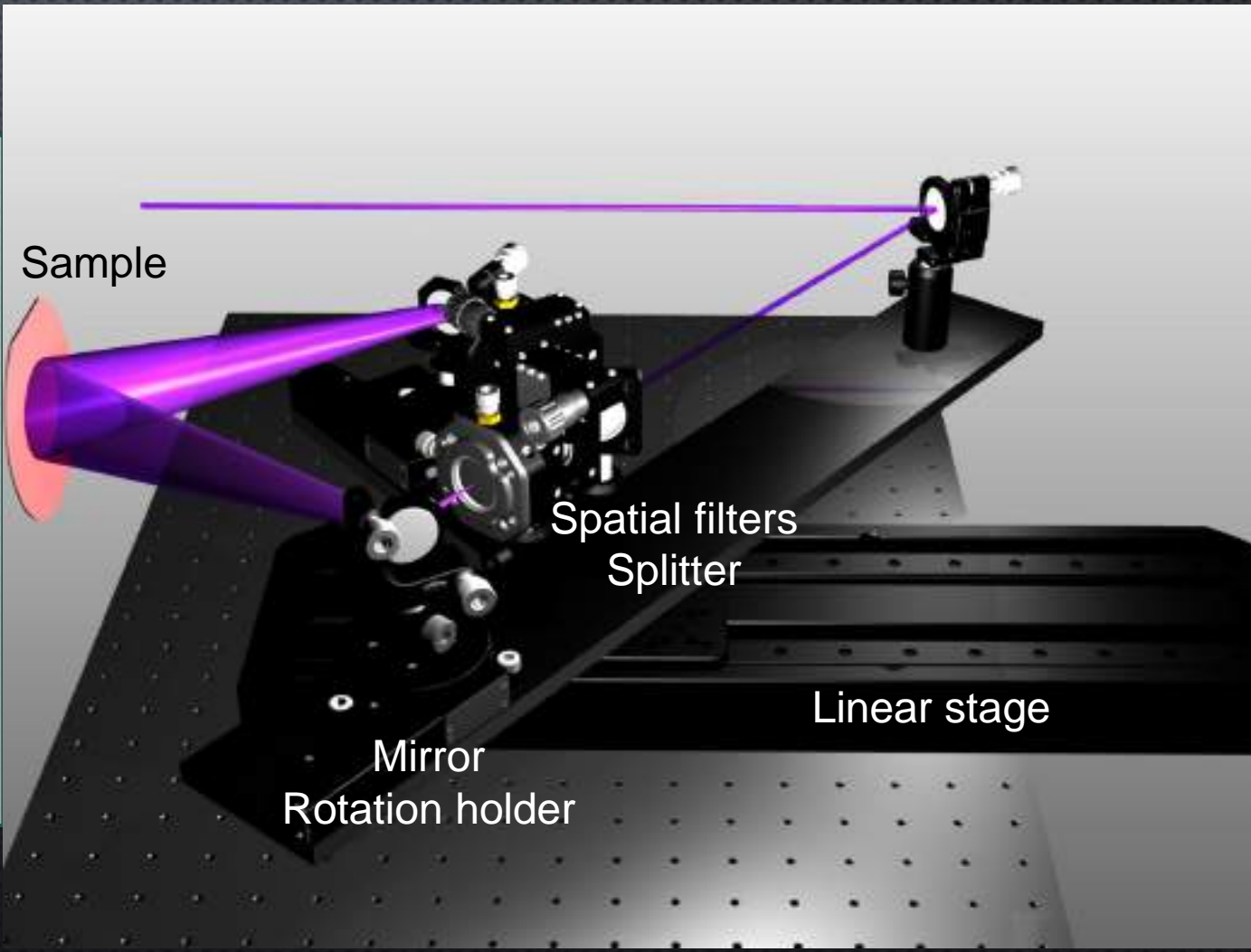
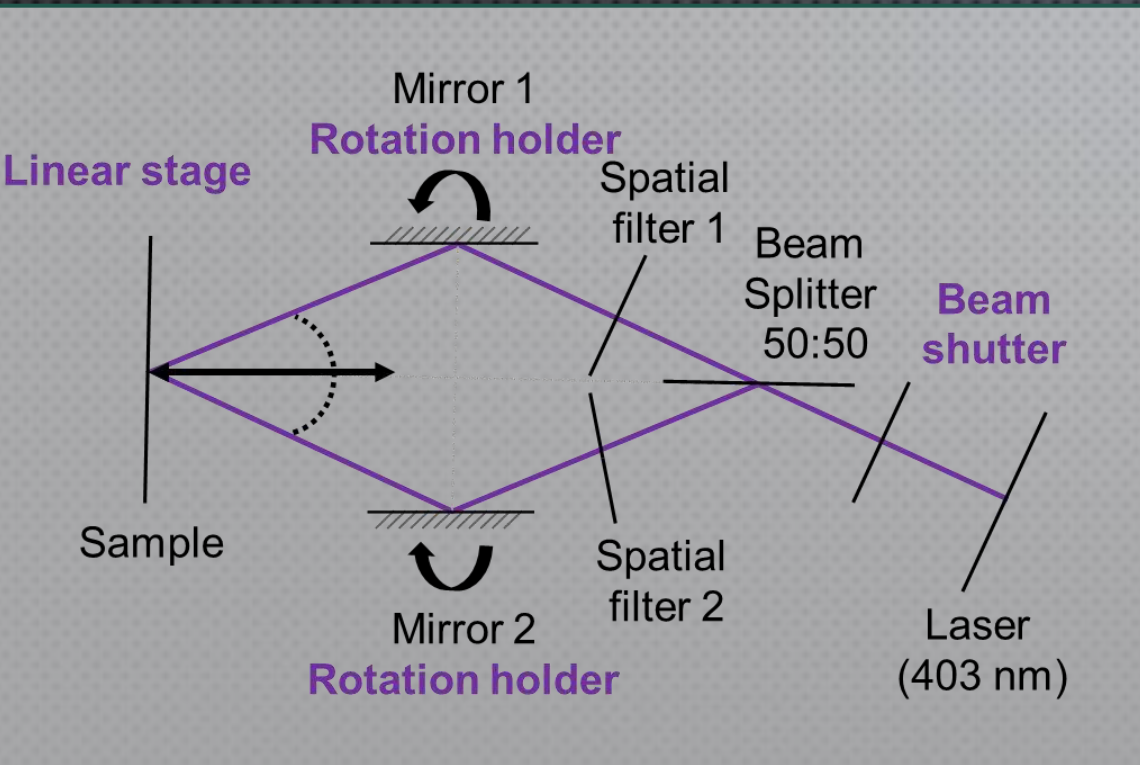
Resulting field

12/21

# Period mixing: setup design

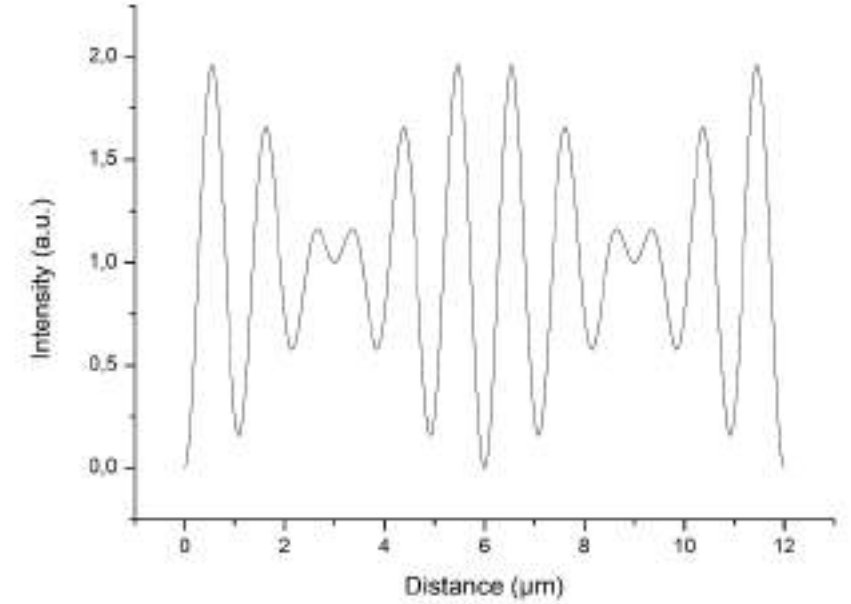
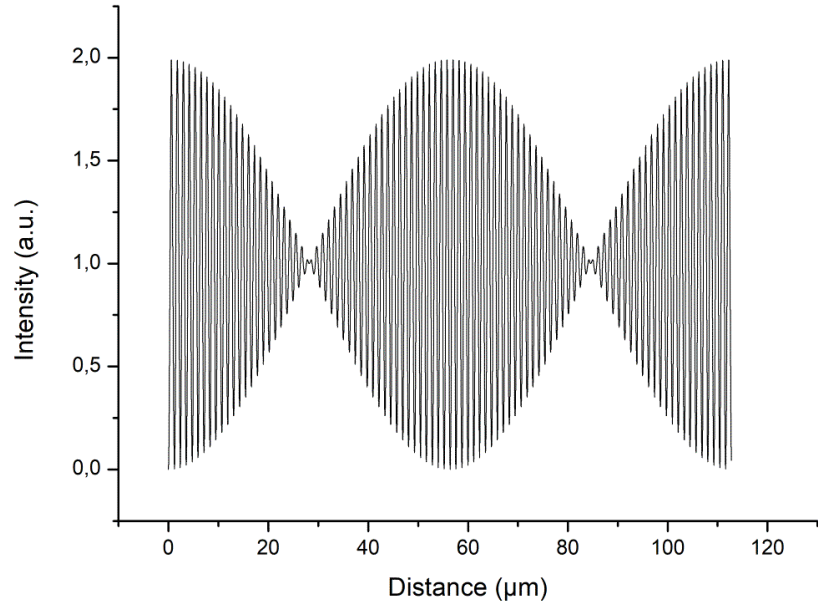
Static sample, moving optics

Moving sample, static optics



LabVIEW controlled and fully automated

# Period mixing: structures design and simulation

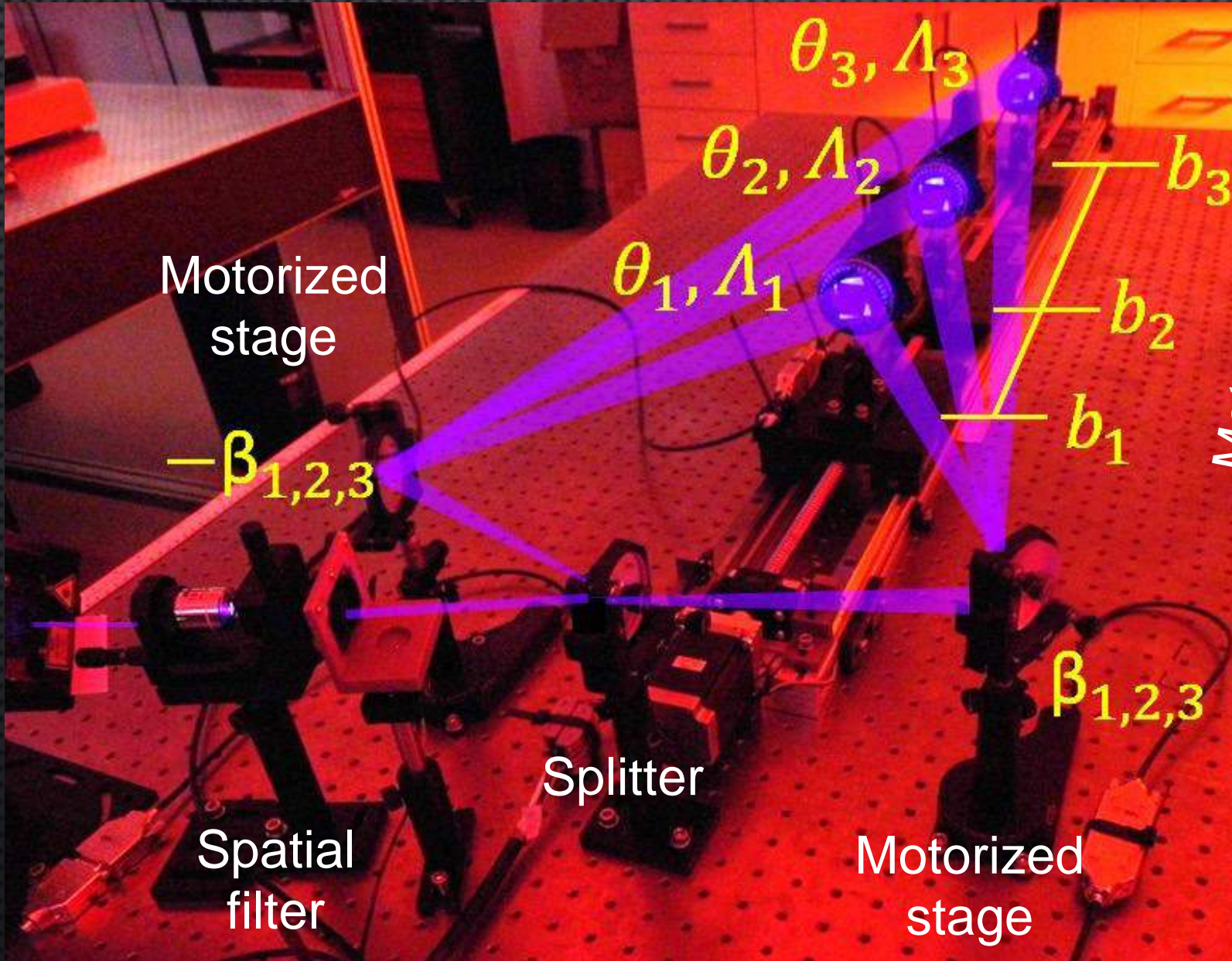


**Small period  
difference  
=  
Large period Grating**

	1	2	3	4
Wave 1 [μm]	1.200	1.200	1.200	1.200
Wave 2 [μm]	1.195	1.175	1.100	1.000
Δ diff. [μm]	0.005	0.025	0.100	0.200
Envelope [μm]	287	56	13	6
Internal [μm]	1.197	1.187	1.148	1.091

**Large period  
difference  
=  
Small period Grating  
14/21**

# Laser interference lithography experimental setup



Single exposure:  
250 – 1000 nm

Period mixing:  
250 – 250 000 nm

Exposure dose

Period tuning

Sample rotation



**Small period  
difference**

**=**

**Large period  
Grating**

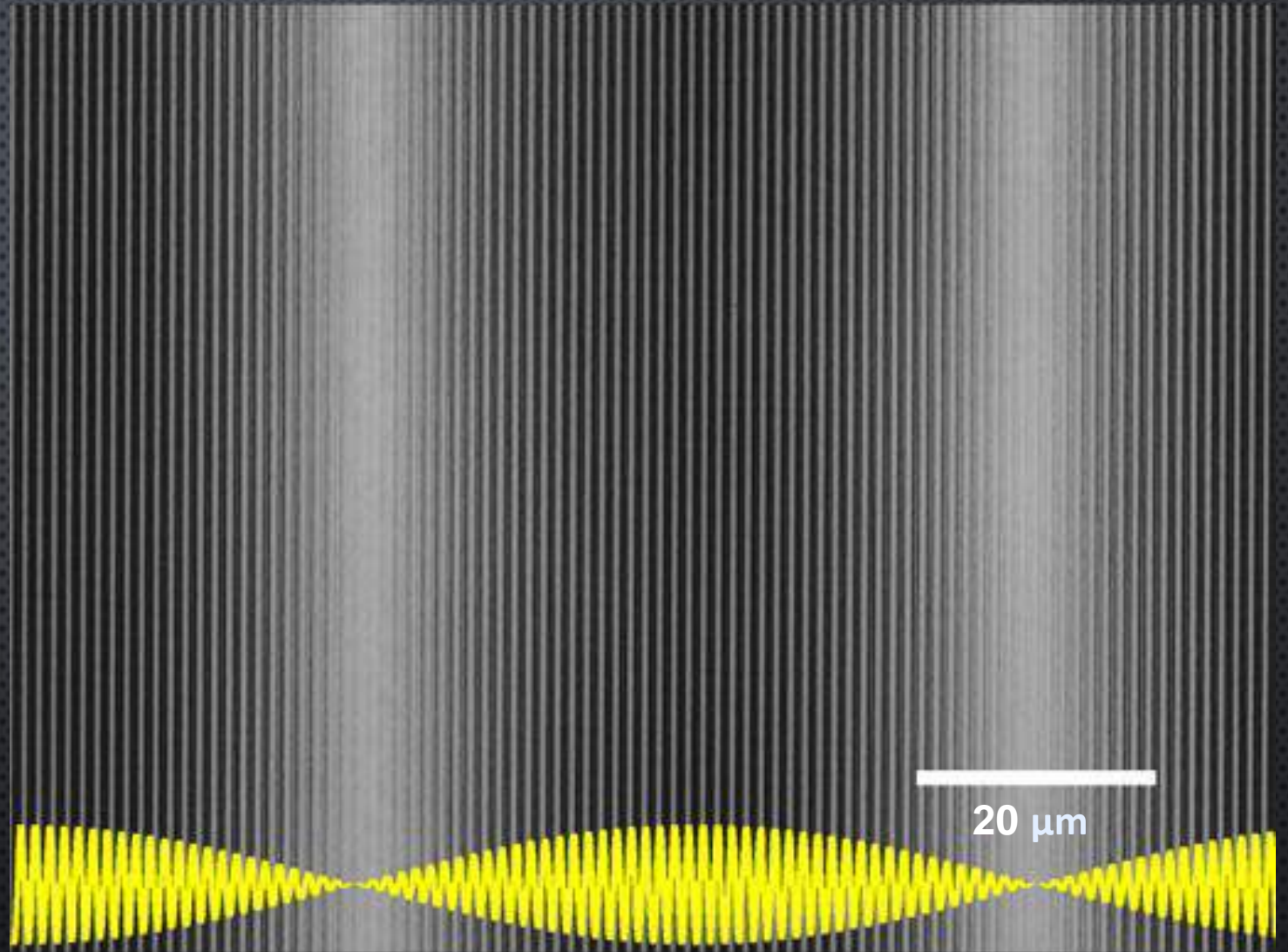
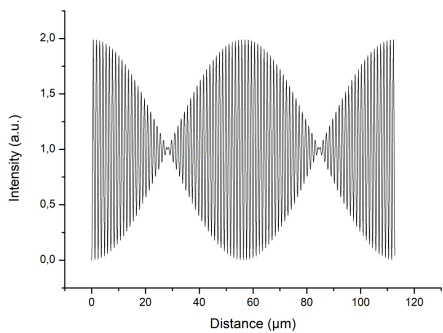
**Period 1:** 1200 nm

**Period 2:** 1175 nm

**Period diff:** 25 nm

**Envelope:** 56 000 nm

**Internal:** 1187 nm





Large period  
difference

=

Small period  
Grating

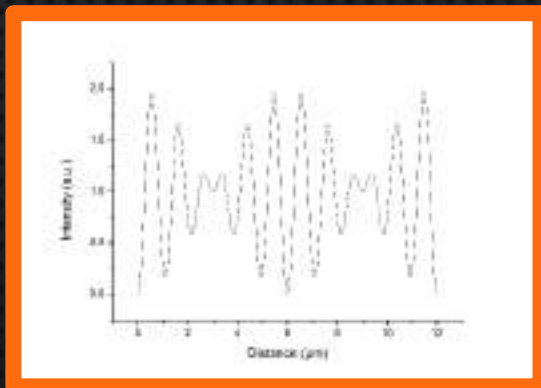
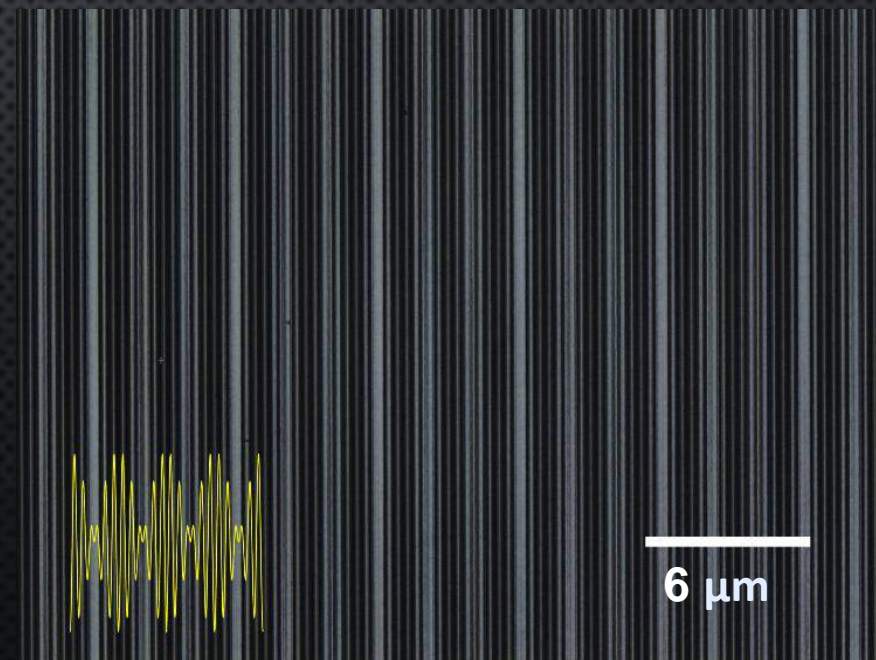
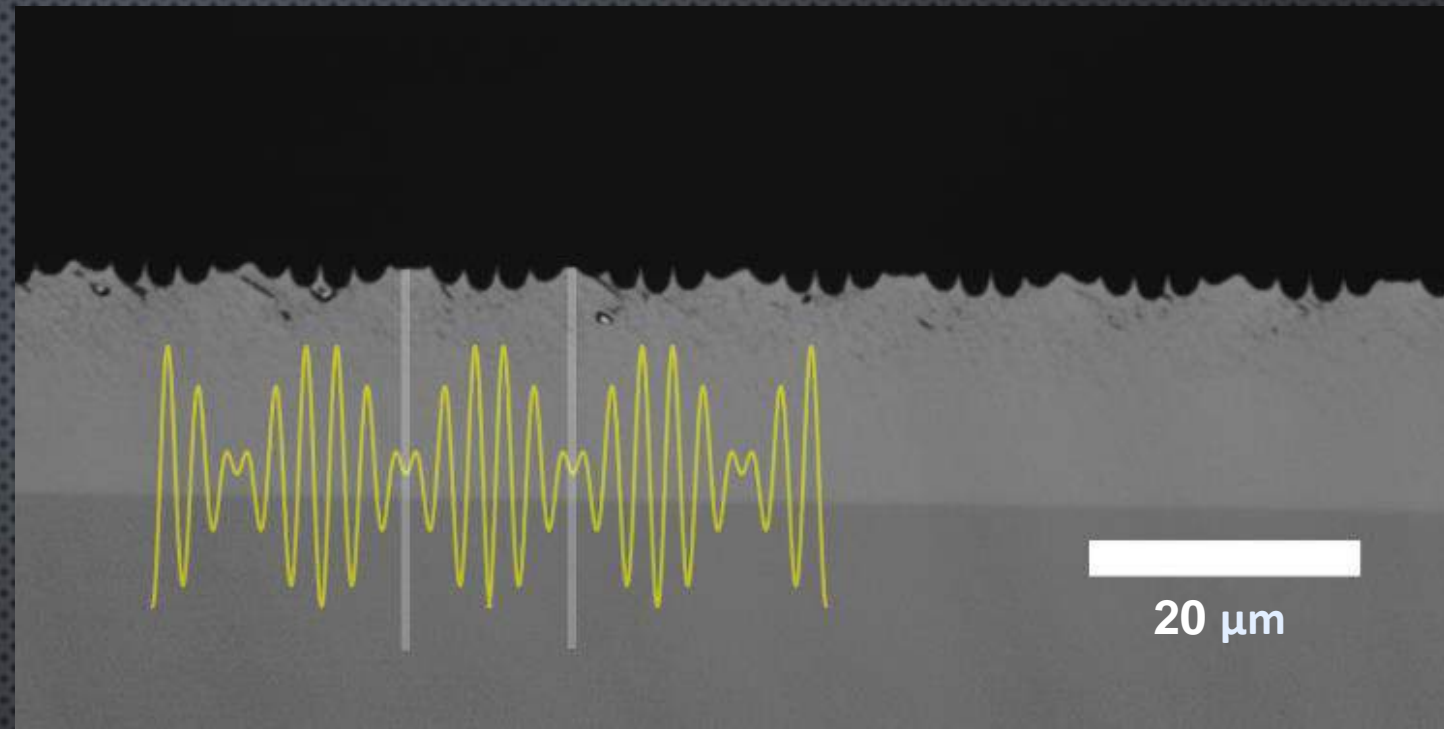
Period 1: 1200 nm

Period 2: 1000 nm

Period diff: 200 nm

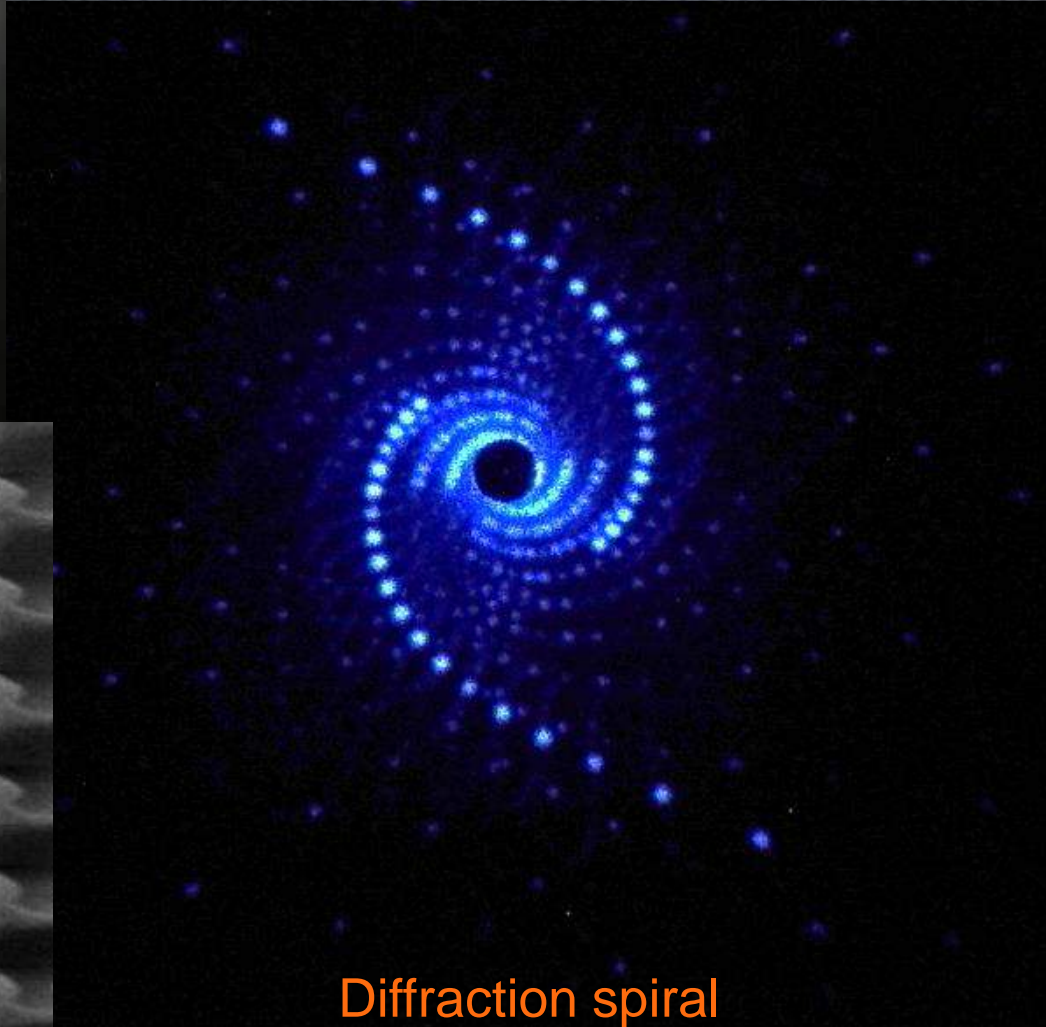
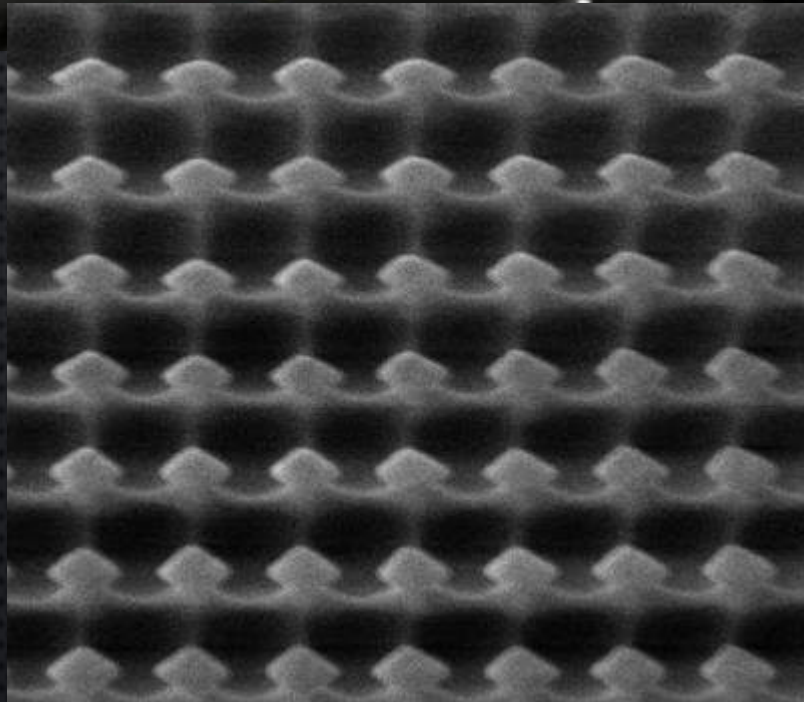
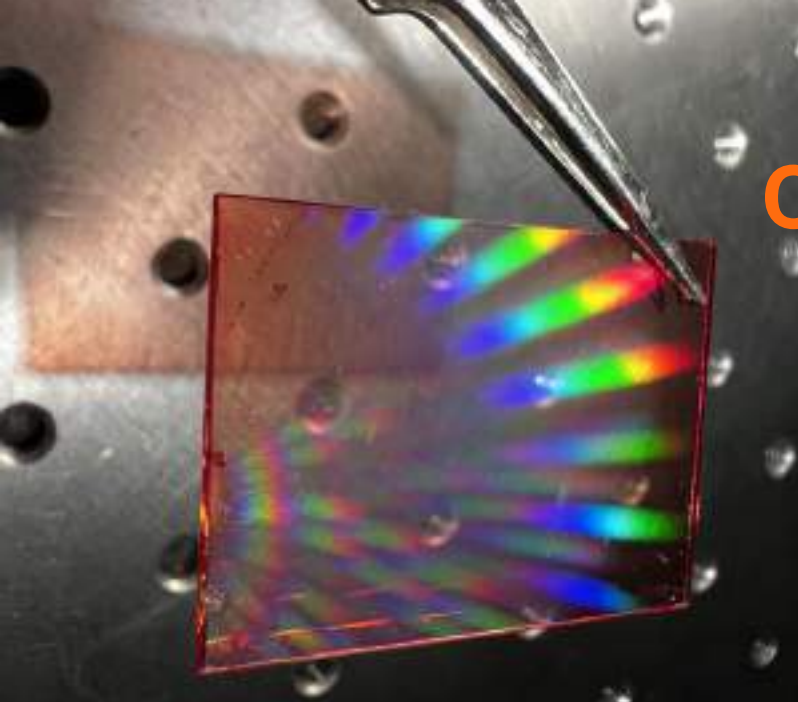
Envelope: 6000 nm

Internal: 1091 nm

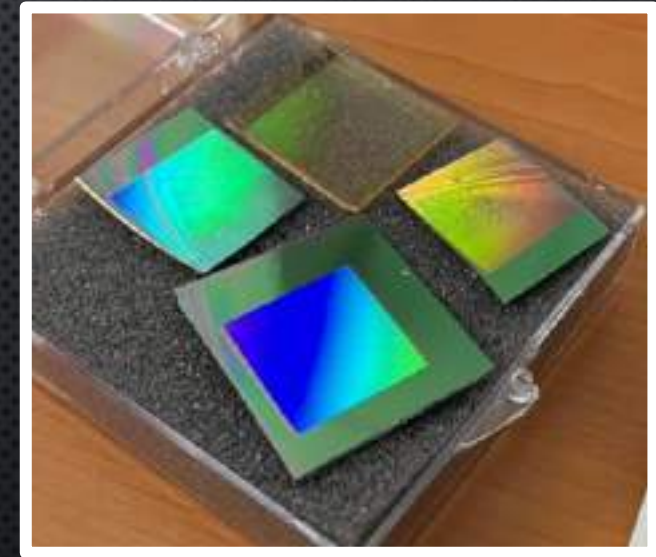


# Complicated symmetries

## Change of period & rotation

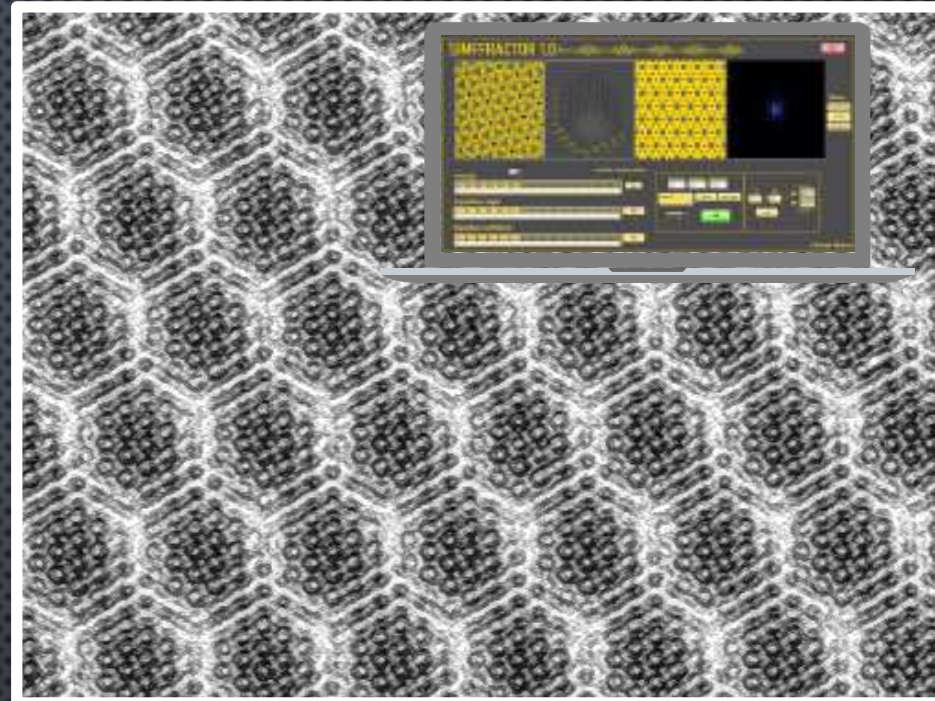
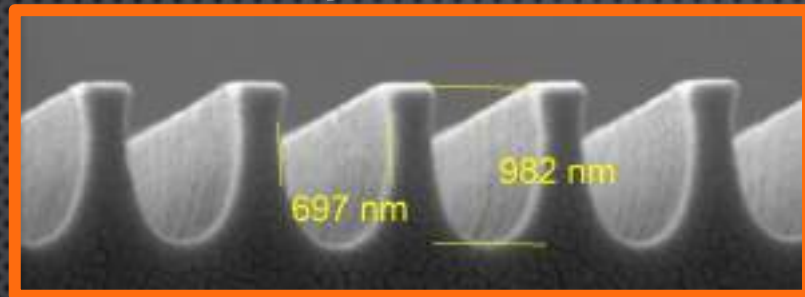


Diffraction spiral  
(20 periods mixed)

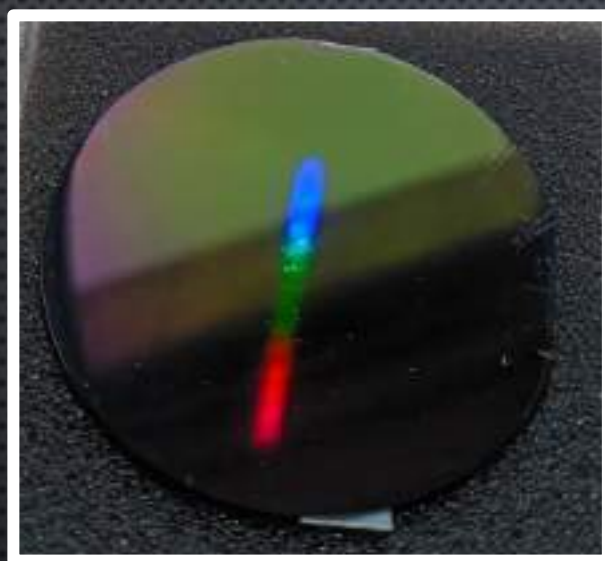
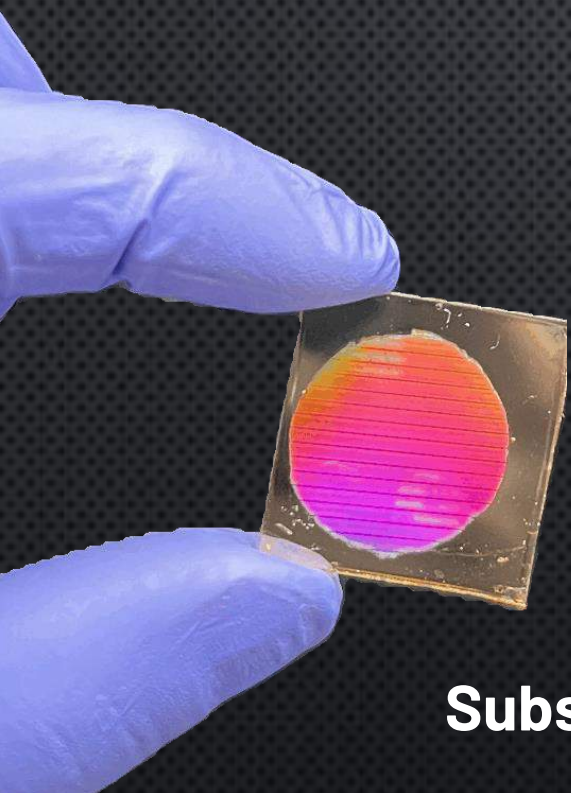


# Thank **you** for your attention

**High aspect ratio**



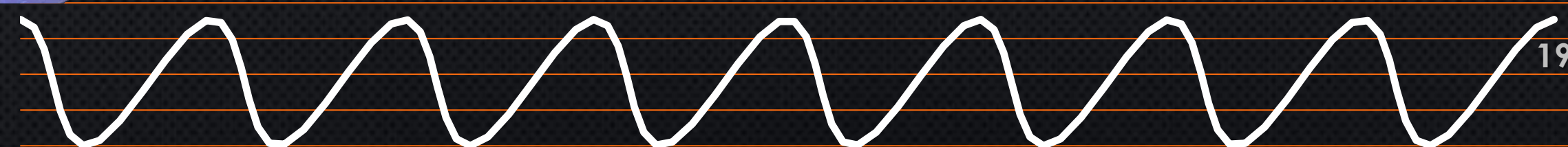
**Moiré structures**



**Substrates: glass, silica, other**

**250 nm ↔ 250 000 nm**

**Tilted blazed structures**



# THANK YOU FOR YOUR ATTENTION!

## Contact details

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*UZA*

*dusan.pudis@feit.uniza.sk*

*+421 41 513 2300*



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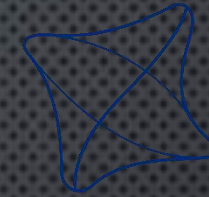
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# Partners' logos

- To be used in the slides



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